Noise Parameter Optimization of UHV/CVD SiGe HBT's for RF and Microwave Applications

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Abstract—This paper demonstrates a predictive noise parameter estimation methodology for UHV/CVD SiGe HBT's which combines ac measurement, calibrated ac simulation and two of the latest Y-parameter-based noise models: 1) the thermodynamic noise model, and 2) the SPICE noise model. The bias current and frequency dependence of the minimum noise figure, the optimum generator admittance, and the noise resistance are calculated using both models and compared with measurements. The observed agreements and discrepancies are investigated using circuit analysis of the chain noisy two-port representation. For the devices under study, the SPICE model description of thermal noise produces a better overall agreement to data in terms of all the noise parameters. Experiments on devices with different collector doping levels show that both low noise and high breakdown voltage can be realized with one profile without significantly compromising the ac current gain and the ac power gain.

Index Terms—AC simulation, bipolar technology, chain noisy two-port representation, low noise amplifier (LNA), noise figure, SiGe HBT, SPICE, thermodynamic noise model.

I. INTRODUCTION

FOR low-noise RF and microwave applications, the SiGe transistor profile and layout need to be optimized to achieve a minimum noise figure. Noise measurements in the GHz range require substantial experimental effort, and the optimization of a low-noise device (including layout, doping and Ge profile) through fabrication and measurement iteration can be very expensive and time consuming. The purpose of this work is to explore the feasibility of predictive noise parameter estimation in UHV/CVD SiGe HBT's by combining ac numerical simulation and two of the latest Y-parameter-based noise models: 1) the thermodynamic noise model [1], and 2) the SPICE noise model [2]. The two-dimensional (2-D) device simulator MEDICI [3] was used in place of ac measurement on fabricated devices, and the simulated Y-parameters are subsequently used to calculate the noise parameters using an in-house post-processing program. The device structure including the 2-D doping profile transitions and physical

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model coefficients was calibrated to ac measurements up to 40 GHz. Although the noise parameters can be calculated from either ac measurements or ac simulation, the use of ac simulation enables specific Ge and doping profile optimization without real time fabrication. A systematic analysis of the difference between the two noise models is performed to gain insight into the results and provide guidelines for practical optimization purposes using simulation. Profile design issues for both low noise and high breakdown voltage applications are also discussed.

II. DEVICE TECHNOLOGY AND MEASUREMENT SETUP

The SiGe HBT's were fabricated using a self-aligned epitaxial-base technology [4]. Fig. 1 shows a schematic cross section of the device. The SiGe base is formed in an ultrahigh-vacuum/chemical vapor deposition (UHV/CVD) low temperature epitaxy (LTE) system. Polysilicon deposited over the field oxide during the LTE serves as the extrinsic base contact. Polysilicon-filled, closed-bottom, deep trenches isolate adjacent subcollectors, and the field oxide is fabricated using a planar shallow trench process. For standard devices in the technology, the intrinsic collector was formed by a double implantation to realize high performance. Representative vertical doping and Ge profiles of the standard SiGe HBT are shown in Fig. 2. For RF power applications, devices with a higher breakdown voltage were fabricated on the same wafer by leaving out one of the collector implantations [5]. We will refer to the device with a double collector implant, and the single collector implant device, as the "standard" device (BV_{CEO} = 3.3 V) and "high BV_{CEO}" device ($BV_{CEO} = 5.3$ V), respectively.

DC characteristics were measured on-wafer using an HP4155, and ac characteristics were measured on-wafer using an HP8510C network analyzer. The noise figure of a $0.5 \times 20 \times 2 \ \mu\text{m}^2$ standard device was measured from 2 to 18 GHz using an NP-5 on-wafer measurement system from ATN Microwave Inc. A summary of the electrical characteristics is given in Table I.

III. NOISE MODELS

In most of the SPICE (e.g., HSPICE, PSPICE, or Smart-Spice) and harmonic balance simulators (e.g., Libra), the nonlinear noise model for BJT's is described by two shot noise current generators flowing from the base and collector to the emitter and two thermal noise voltage generators at the



Fig. 1. Schematic cross section of the UHV/CVD SiGe HBT used in this investigation.



Fig. 2. Representative SIMS doping and Ge profiles of the UHV/CVD SiGe HBT's.

TABLE I Summary of Device Electrical Characteristics ($A_E=0.5\times20\times2~\mu\,{\rm m}^2$)

	Standard Device	High BV _{CEO} Device
Peak β	110	95
Peak f _T (GHz)	51	33
Peak f _{max} (GHz)	64	40
$R_B(\Omega) @ I_c=10mA$	8.9	10.2
$BV_{CEO}(V)$	3.3	5.3

base and emitter, as shown in Fig. 3. An analytical equation of the minimum noise factor (F_{\min}) was derived recently in terms of the Y-parameters, the series base resistance r_B , and emitter resistance r_E [2] [see (1) and (2), shown at the bottom of the page], where $r_{BE} \equiv r_B + r_E$, and I_C and I_B are collector and base currents, respectively. The base and emitter resistances need to be extracted from experiment or simulation. The optimum generator admittance at which F_{\min} occurs for a given bias point and frequency is given by [2]

$$Y_{G,\text{opt}} = G_{G,\text{opt}} + jB_{G,\text{opt}} \tag{3}$$

where

$$G_{G,\text{opt}} = \sqrt{\frac{I_B |Y_{21}|^2 + I_c |Y_{11}|^2}{\frac{2kT}{q} |Y_{21}|^2 r_{BE} + I_c} - \left(\frac{I_c \operatorname{Im}\{Y_{11}\}}{\frac{2kT}{q} |Y_{21}|^2 r_{BE} + I_c}\right)^2}$$
(4)

$$B_{G,\text{opt}} = \frac{-\text{Im}\{Y_{11}\}}{\frac{2kT}{q}|Y_{21}|^2 r_{BE}/I_c + 1}.$$
(5)

The noise resistance R_n relating to the input-referred noise voltage $\langle v_n^2 \rangle$ is given by [2]

$$R_n \equiv \frac{\langle v_n^2 \rangle}{4kT\Delta f} = \frac{I_c}{\frac{2kT}{q}|Y_{21}|^2} + r_{BE}.$$
(6)

Note that the first part of the input-referred noise voltage comes from the collector shot noise $2qI_C$, and the second part comes from the base and emitter resistances.

The other description of transistor noise is the so-called thermodynamic approach [1]. The shot noise generators are the same as in the SPICE models, however, the thermal noise is represented by an input noise current generator $S_I = 4kT$ $\text{Re}(Y_{11})$, which is derived from the fluctuation-dissipation theorem or generalized Nyquist expression for two poles near equilibrium [1], as shown in Fig. 4. Note that the thermal noise current generator operates on the whole transistor including parasitic base and emitter resistances and directly relates to the input Y-parameters. As a result, the noise parameters can be directly calculated from Y-parameters without extracting r_B and r_E , which provides significant time saving for the

$$F_{\min} = 1 + \frac{qI_c}{KT|Y_{21}|^2} (\operatorname{Re}\{Y_{11}\} + A)$$
(1)

$$A = \sqrt{\left[1 + \frac{2kT|Y_{21}|^2 r_{BE}}{qI_c}\right] \left[|Y_{11}|^2 + \frac{I_B|Y_{21}|^2}{I_c}\right] - (\operatorname{Im}\{Y_{11}\})^2} \tag{2}$$



Fig. 3. Schematic of the SPICE noise model. The thermal noise is described by low-voltage noise sources due to the parasitic base and emitter resistance.

optimization of noise figure at a particular frequency. The extraction of r_B and r_E using the impedance circle method requires the simulation of Y-parameters at multiple frequencies even if the noise figure is optimized for only a single frequency. The resulting minimum noise factor equation for the thermodynamic model is [6], [7]

$$F_{\min} = 1 + \frac{I_B + \frac{2kT}{q} \operatorname{Re}\{Y_{11}\} + I_c \left[\frac{\operatorname{Re}\{Y_{11}\} + G_{G, \operatorname{opt}}}{|Y_{21}|}\right]^2}{2G_{G, \operatorname{opt}}kT/q}$$
(7)

where $G_{G,\text{opt}}$ is the real part of the generator admittance (or source conductance) at minimum noise factor [7]

$$G_{G,\text{opt}} = \sqrt{(\text{Re}\{Y_{11}\})^2 + |Y_{21}|^2 \frac{2I_B + 4 \text{ Re}\{Y_{11}\}kT/q}{2I_c}}.$$
(8)

The imaginary part of the generator admittance at minimum noise factor is equal to the conjugate of the imaginary part of the input admittance of the transistor [7]

$$B_{G,\text{opt}} = -\text{Im}\{Y_{11}\}.$$
 (9)

Note that (9) is different from (5). Detailed discussion of why they are different will be given below. The noise resistance R_n relating to the input-referred noise voltage $\langle v_n^2 \rangle$ is given by

$$R_n = \frac{I_c}{\frac{2kT}{a}|Y_{21}|^2}.$$
 (10)

Note that the second term in the right hand side of (6) does not exist in (10) because

- 1) the thermal noise is taken into account through an input current source;
- the input-referred noise voltage is obtained by short circuiting the input and calculating the input voltage generating equal output noise;
- 3) and thus, the thermal noise, when described by an input current noise source, does not contribute to the inputreferred noise voltage, and hence does not contribute to the noise resistance R_n .



Fig. 4. Schematic of the thermodynamic noise model based on fluctuation-dissipation theorem for two poles near equilibrium. The thermal noise is described by an input current noise source associated with the real part of Y_{11} .

Independent of the noise model used, the noise factor for any arbitrary generator admittance $Y_G = G_G + jB_G$ is given by the following universal relation pertaining to a linear noisy two-port [8]:

$$F = F_{\min} + \frac{R_n}{G_G} |Y_G - Y_{G,opt}|^2.$$
 (11)

Equation (11) forms the basis of noise factor measurement and is widely used in circuit design. The reflection coefficient $\Gamma_{G,\text{opt}}$, instead of the admittance $Y_{G,\text{opt}}$ is often used in noise measurements

$$\Gamma_{G,\text{opt}} = \frac{1 - Y_{G,\text{opt}} Z_0}{1 + Y_{G,\text{opt}} Z_0}$$
(12)

where Z_0 is the characteristic impedance and equal to 50 Ω here.

IV. AC DEVICE SIMULATION

In our approach, the physical model coefficients such as the bandgap narrowing (BGN) parameters in Si and SiGe are first calibrated so that both the measured dc and ac characteristics are reasonably reproduced from simulation. Incomplete ionization was intentionally turned off because of the lack of models for the semiconductor-metal transition effect [9] at high doping levels which are important for the base resistance estimation. At concentrations higher than 10^{18} cm⁻³, the impurity band enters into the majority carrier band, so the original concept of separate bands loses meaning, and the dopants are completely ionized. The base majority carrier concentration was severely under-estimated at doping levels above 10¹⁸ cm^{-3} when the incomplete ionization option was turned on. This is particularly important when simulating the "true" SiGe HBT's with an even higher base doping $(10^{19} \text{ cm}^{-3})$. To the authors' knowledge, no commercial device simulator has built-in models for the semiconductor-metal transition effect. The Philips Unified Mobility Model (PHUMOB) was selected and found to produce sensible results due to its unique consideration of minority carrier mobility. The lateral field dependence of mobility (FLDMOB) was selected to accurately simulate the collector-base junction capacitance because the CB junction electric field is strong enough to cause velocity saturation even at V_{CB} close to 0 V due to the high collector doping required for optimum performance. Bandgap narrowing due to heavy doping was selected due to the high doping levels in HBT's. However, the bandgap narrowing parameters need to be adjusted in accordance with the type of statistics selected

NSRHN (cm ⁻³) SiGe	10 ¹⁹
NSRHN (cm ⁻³) Si	10 ¹⁷
NSRHP (cm ⁻³) SiGe	10 ¹⁹
NSRHP (cm ⁻³) Si	10 ¹⁷
TAUN0 (second)	6×10 ⁻⁹
TAUP0 (second)	2×10 ⁻⁹
V0.BGN (eV) Si	5.0858×10 ⁻³
N0.BGN (cm ⁻³)	1.3×10 ¹⁷
CON.BGN	0.5
V0.BGN (eV) SiGe	4.1128×10 ⁻³

(Boltzmann or Fermi-Dirac statistics) because of the difference between the apparent bandgap narrowing and the physical bandgap narrowing, as reviewed in [10]. The simulations here were done using Fermi-Dirac statistics. Table II shows the typical MEDICI model coefficients calibrated for the devices under study. Default values were used for those parameters not listed in Table II. The 2-D device structure was constructed based on vertical SIMS profiles taken through the center of the emitter and the extrinsic base. These vertical doping and Ge profiles are kept as is in the simulation and only the parameters for physical models such as bandgap narrowing and the lateral transition of doping profiles were adjusted in the calibration. The purpose is to enable the doping and Ge profile optimization for minimum noise figure using the same set of physical model coefficients calibrated for this technology. A finer grid was generated self-consistently in places with a larger potential gradient, Ge gradient or doping gradient. The lateral transition between extrinsic and intrinsic base was determined by best-fitting the simulated and measured base resistance. The lateral transition between extrinsic and intrinsic collector was determined by best-fitting the simulated and measured collector-base capacitance. The Y-parameters are simulated in MEDICI by solving the system of semiconductor transport equations in the frequency domain.

An examination of the two noise factor equations (1) and (7) shows that F_{\min} from both models strongly depend on Y_{11} and Y_{21} . Therefore, our model calibration approach is intended to reproduce not only the cutoff frequency and maximum oscillation frequency, as is the typical approach for model calibration, but also each individual Y-parameter. Although there are many 2-D simulation parameters that one can adjust, determining a single set of simulation parameters that can reproduce the four complex network parameters at all the biases of interest (0.1–1.0 mA/ μ m²) for frequencies up to 40 GHz requires substantial effort. An in-depth understanding of the interaction of physics of the simulation models and device operation is especially important for achieving sensible results. For instance, at lower current, the total transit time is dominated by the time constants relating to the EB space charge region capacitance rather than the diffusion capacitance. Therefore, the adjustment of mobility parameters in the base affects only the cutoff frequency at higher current level



Fig. 5. Comparison of simulated and measured real part of Y_{11} , which enters into the NF_{min} equations for both the SPICE noise model and the thermodynamic noise model ($I_C = 4.1$ mA and $A_E = 0.5 \times 20 \times 2 \ \mu$ m²).



Fig. 6. Comparison of simulated and measured imaginary part of Y_{11} , which enters into the SPICE noise model NF_{\min} equation (1) ($I_C = 4.1$ mA and $A_E = 0.5 \times 20 \times 2 \ \mu \text{m}^2$).



Fig. 7. Comparison of measured and simulated magnitude of Y_{21} , which enters into the NF_{\min} equations for both the SPICE noise model and the thermodynamic noise model ($I_C = 4.1 \text{ mA}$ and $A_E = 0.5 \times 20 \times 2 \mu \text{m}^2$).

and does not help the lower current level calibration. On the contrary, the peak cutoff frequency value and its roll-off due to the Kirk effect are mainly determined by the time constants relating to the EB diffusion capacitance and hence mobility parameters, as well as the velocity saturation parameters.

Figs. 5–7 show the comparison of the simulated and measured real part of Y_{11} , the imaginary part of Y_{11} , and the magnitude of Y_{21} versus frequency at $I_C = 4.1$ mA for a $0.5 \times 20 \times 2 \ \mu m^2$ SiGe HBT. These three parameters closely relate to the noise parameters in the SPICE noise model, as can be seen from (1). Two of these parameters (Re $\{Y_{11}\}$ and Mag $\{Y_{21}\}$) closely relate to the noise parameters in the thermodynamic model. The calibrated simulation agrees well with measurement for all the three Y-parameters, particularly below 20 GHz, and therefore can be used for further noise parameter estimation. NIU et al.: NOISE PARAMETER OPTIMIZATION OF UHV/CVD SIGE HBT'S

V. SIMULATION OF NOISE PARAMETERS

Having verified the accuracy of the calibrated 2-D simulation, we proceed with the calculation of the noise parameters using the simulated Y-parameters. Results from both noise models are compared to the measured data to explore their differences. For a complete verification, we examine the current and frequency dependence of all of the three noise parameters including the minimum noise factor F_{\min} (through the minimum noise figure $NF_{\min} = 10\log(F_{\min})$), the optimum admittance $Y_{G,\text{opt}}$ (through $\Gamma_{G,\text{opt}}$), and the noise resistance R_n .

A. The Minimum Noise Factor F_{\min} (Through Minimum Noise Fig. $NF_{\min} = 10 \log F_{\min}$)

First, the base and emitter resistance needs to be extracted for the SPICE noise model. In [2], the base and emitter resistances were determined separately using the averaged real part of $Z_{11} - Z_{12}$ and Z_{12} at frequencies below 1 GHz. We observe here that the sum of the base and emitter resistances $r_{BE}(r_{BE} \equiv r_B + r_E)$, which enters into the noise parameter equation of the SPICE noise model, can be directly determined from the left intercept of the semi-circle on the complex plane of the input impedance. Using a 50- Ω characteristic impedance, the input impedance high-frequency intercept is readily obtained from the equivalent circuit in Fig. 3 by shorting all the three internal terminals of the intrinsic transistor

$$Z_{\rm in} = r_B + r_E //50 \ \Omega$$
$$\approx r_B + r_E \tag{13}$$

because the emitter resistance is usually far less than 50 Ω . In best fitting the simulated input impedance, the low-frequency data are favored against the high-frequency data because the lumped equivalent circuit description of transistor operation is no longer accurate at very high frequencies.

Figs. 8 and 9 show the simulated and measured minimum noise figure $(NF_{\min} = 10 \log F_{\min})$ versus collector current at 2 and 10 GHz, respectively. The agreement between simulation using both noise models and measurement is close at 10 GHz. At 2 GHz, for the operating current where the NF_{min} is minimum, the agreement between simulation and measurement is also close. Fig. 10 shows the simulated minimum noise figure versus frequency at $I_C = 1.26$ mA, a relatively low current value giving the minimum NF_{min}. Considering the on-wafer noise measurement accuracy, the agreement between simulation and measurement is excellent across 2-18 GHz, a frequency range at which these SiGe HBT's are best suited to operate. This indicates that both Y-parameter-based noise models can be used in this low current density region which is of practical interest for NF_{\min} and that such an ac simulationnoise model approach can be used for predictive noise figure optimization.

B. The Optimum Generator Admittance $Y_{G,\text{opt}}$ ($\Gamma_{G,\text{opt}}$)

The other important noise parameter is the optimum generator admittance $Y_{G,\text{opt}}$, which is often characterized by the reflection coefficient at minimum noise figure ($\Gamma_{G,\text{opt}}$) in



Fig. 8. Comparison of measured and simulated noise figure versus collector current using both noise models at 2 GHz.



Fig. 9. Comparison of measured and simulated noise figure versus collector current using both noise models at 10 GHz.



Fig. 10. Comparison of measured and simulated noise figure versus frequency at $I_C=1.26\,$ mA.

measurement. Given that both models give NF_{\min} values reasonably close to the data, it is interesting to see how the optimum admittance $Y_{G,opt}$ compares to the measured data. Figs. 11 and 12 show the magnitude and angle of the optimum reflection coefficient $\Gamma_{G,\text{opt}}$ [defined in (12)] versus collector current at 2 GHz, and Figs. 13 and 14 show the same comparisons at 10 GHz. Although the qualitative behavior is similar for the two models, the SPICE noise model shows a closer agreement to the measured data, particularly at 2 GHz. This indicates that for the devices under study, the physical description of thermal noise in the SPICE model is more appropriate. Figs. 15 and 16 show the magnitude and angle of the $\Gamma_{G,\text{opt}}$ versus frequency at $I_C = 1.26$ mA, a relatively low current value giving the minimum NF_{\min} at all the frequencies of interest. At such low currents, comparable to those in low-noise amplifier applications, both models can reasonably reproduce the measured optimum admittance. Therefore, from a simulation perspective, the thermodynamic model is still preferred in low-noise device design at low current for a



Fig. 11. Comparison of measured and simulated magnitude of the optimum reflection coefficient versus collector current using both noise models at 2 GHz.



Fig. 12. Comparison of measured and simulated angle of the optimum reflection coefficient versus collector current using both noise models at 2 GHz.



Fig. 13. Comparison of measured and simulated magnitude of the optimum reflection coefficient versus collector current using both noise models at 10 GHz.

given frequency. The SPICE model, however, needs the base resistance, the extraction of which requires a semi-circle in the input-impedance plane, and hence requires simulation at multiple frequencies. However, if the application requires higher operation current, the SPICE model needs to be used for an accurate source matching network design.

C. The Noise Resistance R_n

The associated gain of a device at minimum noise figure may not be sufficient for application as a low-noise amplifier. In this situation, a compromise between input matching for minimum noise figure and for power gain can be made. The noise resistance R_n determines the sensitivity of the total noise figure to deviations from optimum noise admittance matching



Fig. 14. Comparison of measured and simulated angle of the optimum reflection coefficient versus collector current using both noise models at 10 GHz.



Fig. 15. Comparison of measured and simulated magnitude of the optimum reflection coefficient versus frequency at $I_C = 1.26$ mA using both noise models.



Fig. 16. Comparison of measured and simulated angle of the optimum reflection coefficient versus frequency at $I_C = 1.26$ mA using both noise models.

 $Y_{G,\text{opt}}$, as can be seen in (11). According to the linear two-port noise theory, R_n can be determined by the input-referred noise voltage $\langle v_n^2 \rangle$ using (6). Because of the difference in thermal noise consideration, $\langle v_n^2 \rangle$ for the thermodynamic model is due to the $2qI_C$ shot noise only, while the $\langle v_n^2 \rangle$ for the SPICE model has an extra contribution from the base and emitter resistance. Although the two noise models yielded similar NF_{\min} and $Y_{G,\text{opt}}$ at low currents of interest to minimum noise figure, they gave very different equations of R_n . A comparison of R_n from both models with the measurement data will provide further insight into the model differences. Figs. 17 and 18 show the R_n comparison between models and measurement as a function of bias current at 2 and 10 GHz. Fig. 19 shows the R_n comparison as a function of frequency.



Fig. 17. Comparison of measured and simulated noise resistance versus collector current using both noise models at 2 GHz.



Fig. 18. Comparison of measured and simulated noise resistance versus collector current using both noise models at 10 GHz.



Fig. 19. Comparison of measured and simulated noise resistance versus frequency using both noise models at $I_C = 1.26$ mA.

The SPICE model is in close agreement with the measured R_n , which also suggests that the description of thermal noise through the base and emitter resistance is more suitable for the SiGe HBT's used in this work. From a practical point of view, R_n is not important if the device is to operate at noise matching for minimum noise figure. Therefore, the thermodynamic model can still be used for profile optimization due to its low simulation cost discussed earlier. After the design goal for minimum noise factor is achieved, the SPICE model can be used to obtain the optimum admittance and noise resistance. Specific Ge and doping profile optimization for the design of a microwave SiGe HBT with a 2-dB noise figure, and 15 dB associated gain at noise matching for 20 GHz operation using this ac 2-D simulation-noise model approach, will be reported in a separate paper.



Fig. 20. Circuit schematic of the chain noisy two-port representation.

D. Further Probing of the Relations Between the Two Models

Despite a very different consideration of the thermal noise, the traditional SPICE noise model and the thermodynamic noise model lead to nearly identical minimum noise figure and optimum noise matching admittance at low current in the devices under study. The noise resistance, however, differs by the amount of base and emitter resistance between the two models. An interesting question is how to understand the observed agreements and discrepancies. The essential differences between two models are two-fold: 1) The thermal noise source in the SPICE model is determined by the series resistance, while the thermal noise source in the thermodynamic model is determined by the real part of input Y parameter (Y_{11}) . 2) The thermal noise in the SPICE model is represented by a voltage source in series with the input voltage, while the thermal noise in the thermodynamic model is represented by a current source in parallel with the input current. These differences can be used to explain the observations, as described below.

Any noisy network can be replaced by a chain noise equivalent circuit, which consists of the original two-port (assumed to be noiseless), the correlated input-referred current noise source $\langle i_n^2 \rangle$, and the input-referred voltage noise source $\langle v_n^2 \rangle$ [8], as shown in Fig. 20. Independent of the physical sources of noises inside the device, the four noise parameters can be expressed as a function of $\langle i_n^2 \rangle$, $\langle v_n^2 \rangle$, and their crosscorrelation $\langle v_n i_n^* \rangle$ [8], [11], [12]

$$F_{\min} = 1 + 2(C_r + \sqrt{R_n G_n - C_i^2}) \tag{14}$$

$$G_{G,\text{opt}} = \sqrt{\frac{G_n}{R_n} - \left(\frac{C_i}{R_n}\right)^2}$$
(15)

$$B_{G,\text{opt}} = \frac{C_i}{R_n} \tag{16}$$

$$R_n = \frac{\langle v_n^2 \rangle}{4kT\Delta f} \tag{17}$$

where

$$G_n = \frac{\langle i_n^2 \rangle}{4kT\Delta f} \tag{18}$$

$$C_r = \frac{\operatorname{Re}\{\langle v_n i_n^* \rangle\}}{4kT\Delta f} \tag{19}$$

$$C_i = \frac{\mathrm{Im}\{\langle v_n i_n^* \rangle\}}{4kT\Delta f}.$$
(20)

Table III gives the comparison of $\langle i_n^2 \rangle$, $\langle v_n^2 \rangle$, and the crosscorrelation $\langle v_n i_n^* \rangle$ for the two models obtained by transforming the two noisy two-ports in Figs. 3 and 4 to their chain noisy two-ports through circuit analysis. Details of the circuit analysis are omitted for space limitation. $\langle i_n^2 \rangle$ is obtained by open circuiting the input and dividing the output noise

TABLE III COMPARISON OF $\langle i_n^2 \rangle, \langle v_n^2 \rangle$, and $\langle v_n i_n^* \rangle$ Between the Two Noise Models



Fig. 21. Comparison of the $R_n G_n$ product calculated using the two models.

current by $|H_{21}|^2$, which is $|Y_{21}/Y_{11}|^2$ by definition. $\langle v_n^2 \rangle$ is obtained by short circuiting the input and dividing the output noise current by $|Y_{21}|^2$. The cross-correlation $\langle v_n i_n^* \rangle$ is then calculated using the internal noise sources common to both i_n and v_n , which is the collector shot noise $2qI_C$ in both models.

A careful inspection of the circuit analysis results reveals the following important relations between the two models.

- 1) The cross-correlation $\langle v_n i_n^* \rangle$ and hence C_r and C_i are the same for both models.
- 2) $\langle i_n^2 \rangle$ is the same for both models except for an extra term 4kT Re $\{Y_{11}\}$ in the thermodynamic model.
- 3) $\langle v_n^2 \rangle$ is the same for both models except for an extra term $4kTr_{BE}$ in the SPICE model.
- 4) The product of $\langle i_n^2 \rangle$ and $\langle v_n^2 \rangle$, which determines the $G_n R_n$ product, share two common terms.

Consequently, the difference in R_n , $G_{G,opt}$, and $B_{G,opt}$ between the two models can be readily understood from the difference in $\langle v_n^2 \rangle$, $\langle i_n^2 \rangle$. The minimum noise figure is expected to differ only by the $G_n R_n$ product, as can be seen from (14). Although G_n and R_n are very different for the two models, their product $G_n R_n$, which shares two common terms, could be similar. In that case, similar NF_{\min} values are obtained using both models despite the difference in $Y_{G,opt}$ and R_n . Fig. 21 compares the $G_n R_n$ product calculated using both models at $I_C = 1.26$ mA. The two models give a similar $G_n R_n$ product, which is responsible for the agreement in NF_{\min} shown in Fig. 10.

The thermodynamic model noise factor expression, (7), which was originally derived using the independent internal noise sources [1], can also be derived by substituting the $\langle v_n^2 \rangle$, $\langle i_n^2 \rangle$, and $\langle v_n i_n^* \rangle$ in Table III into the general-purpose noise figure equation for the chain noisy network representation (14). The derivation using the chain noisy two-port is more complex than the original derivation because of the inclusion of the cross-correlation term. However, the chain noisy two-port



Fig. 22. NF_{min} versus I_C of the standard device and the high BV_{CEO} device calculated from measured Y-parameters at 4 GHz.

representation provides a means of comparing models with different physical consideration of the internal noise sources. Comparisons with measurement are also made easier using the chain noisy two-port representation because of the explicit relation between the noise parameters and the noise sources $\langle v_n^2 \rangle$, $\langle i_n^2 \rangle$, and $\langle v_n i_n^* \rangle$.

VI. IMPACT OF COLLECTOR DOPING

A higher breakdown voltage device for power amplifier applications can be achieved in this SiGe technology by leaving out one of the collector implantations. A logical question is: how does the collector profile affect the resultant noise figure? Having verified that the two noise models are accurate at the low-current density of interest for this technology, we have calculated the noise figure of the higher breakdown device (BV_{CEO} = 5.3 V) using the two noise models and measured S-parameters. Comparisons to the standard device $(BV_{CEO} = 3.3 \text{ V})$ at 4 and 10 GHz are shown in Figs. 22 and 23, respectively. Interestingly, the resulting noise figures from both models are nearly identical to the standard device with a double collector implantation for $I_C < 10$ mA, the bias range which is of practical interest. This implies that as far as noise figure is concerned, the higher breakdown device should provide almost the same performance as the standard device. To better understand this result, Figs. 24 and 25 show the other two high-frequency figures-of-merit, transition frequency (f_T) , and maximum oscillation frequency (f_{max}) , respectively, versus collector current for the standard and high BV_{CEO} device. In the current range where NF_{min} is lowest $(I_C < 10 \text{ mA})$, the f_T and f_{max} of the high BV_{CEO} device are comparable to that of the standard device. Therefore, the high BV_{CEO} device provides comparable ac current and power gains and may provide profile leverage in circuits that require not only low noise but also higher breakdown voltage.

VII. CONCLUSIONS

Predictive noise figure calculation in UHV/CVD SiGe HBT's which combines calibrated ac 2-D simulation and *Y*-parameter-based noise models has been demonstrated. A complete comparison of both models with measurement is made for the minimum noise figure, optimum generator admittance, and noise resistance. The observed agreements and discrepancies between the two noise models are explored by comparative circuit analysis of the chain noisy two-ports



Fig. 23. NF_{min} versus I_C of the standard device and the high BV_{CEO} device calculated from measured Y-parameters at 10 GHz.



Fig. 24. Measured f_T versus I_C of the standard device and the high ${\rm BV}_{\rm CEO}$ device.



Fig. 25. Measured $f_{\rm max}$ versus $I_{\rm C}$ of the standard device and the high $BV_{\rm CEO}$ device.

for both models. Experiments show that both low noise and high breakdown voltage can be achieved within one profile at relatively low currents without sacrificing ac current gain and ac power gain.

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